

PATENT ABSTRACTS OF JAPAN

(11)Publication number : 2001-185024

(43)Date of publication of application : 06.07.2001

(51)Int.Cl.

H01J 9/02
C03C 8/04
C03C 17/23
H01J 11/02

(21)Application number : 2000-340515

(71)Applicant : JSR CORP

(22)Date of filing : 25.07.1996

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(30)Priority

Priority number : 07196428 Priority date : 01.08.1995 Priority country : JP

(54) METHOD OF MANUFACTURING PLASMA DISPLAY PANEL

(57)Abstract:

PROBLEM TO BE SOLVED: To provide a method of manufacturing a plasma display panel including a new forming process that enables to efficiently form a dielectric layer having a thicker film.

SOLUTION: This method comprises steps of forming film forming material layer by applying a paste phase composition containing glass powder, acrylic acid eater resin and solvent on a support film, transcribing the film forming material layer forming on the support film onto an outer surface of a glass substrate to which electrodes are fixed, and forming a dielectric layer in the outer surface of the glass substrate by sintering the transcribed film forming material layer.